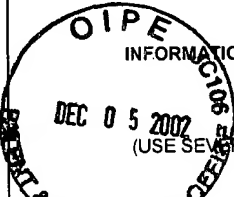


FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMEX.186DV1	APPLICATION NO. 09/764,711
 <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>(USE SEVERAL SHEETS IF NECESSARY)</p>		APPLICANT Raaijmakers et al.	
		FILING DATE January 18, 2001	GROUP 2812

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
DR	1.	5,192,708	3/9/93	Beyer et al.	437	90	4/29/92
	2.	5,371,039	12/6/94	Ogaro	437	101	2/18/93
	3.	5,627,092	5/6/97	Alsmeier et al.	438	152	9/26/94
	4.	5,888,876	3/30/99	Shiozawa et al.	438	386	4/9/94
MR	5.	6,297,088 B1	10/2/01	King	438	243	1/2/00

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

EXAMINER  
INITIAL

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

DR	6.	Arienzo et al., "In Situ Arsenic-Doped Polysilicon for VLSI Applications" Transactions on Electron Devices ED33(1):1535-1538 (1986) J						

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EXAMINER

DATE CONSIDERED

\*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.